

AMENDMENTS TO THE ABSTRACT:

Please replace the present abstract with the following rewritten abstract:

A MOSFET array gas sensor is fabricated using silicon bulk micro machining. A heating resistor, a diode used as temperature sensor and 4 gas-sensitive FETs are located in a silicon island suspended by a dielectric membrane. The membrane has a low thermal conductivity coefficient and therefore thermally isolates the electronic components in the silicon island from the chip frame. This low thermal mass device allows the reduction of power consumption to a value of 80 mW for an operating temperature of 175°C. This low power MOSFETs gas sensor array is suitable for applications in portable gas sensors instruments and in automobiles.

HAYES SOLOWAY P.C.
130 W. CUSHING ST.
TUCSON, AZ 85701
TEL. 520.882.7623
FAX. 520.882.7643

175 CANAL STREET
MANCHESTER, NH 03101
TEL. 603.668.1400
FAX. 603.668.8567